

BSIM-IMG: Surface Potential based UTBSOI MOSFET Model

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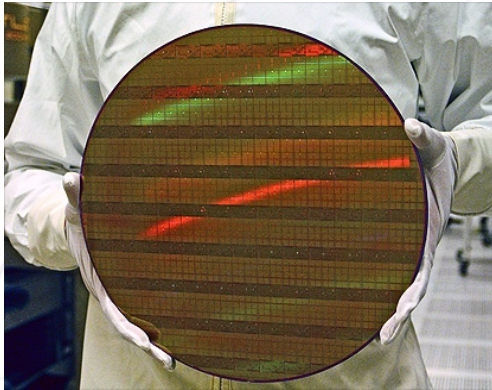


UC Berkeley

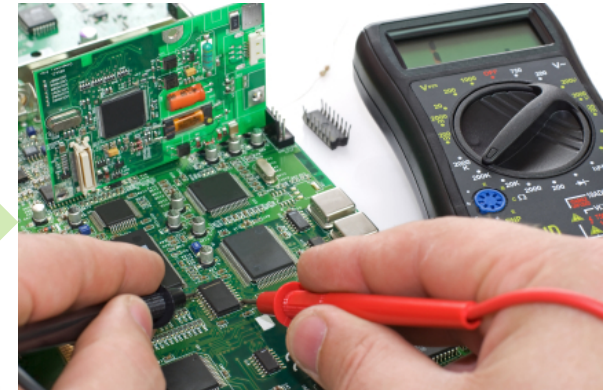
Dec. 15, 2011

The Nano-Tera Workshop on the Next Generation
MOSFET Compact Models, EPFL, Switzerland.

SPICE Transistor Modeling for Circuit Simulation



Medium of
information
exchange



- **Simulation Time**

- $\sim 10\mu\text{s}$ per DC data point
- No complex numerical method allowed

- **Accuracy requirements**

- $\sim 1\%$ RMS Error after fitting

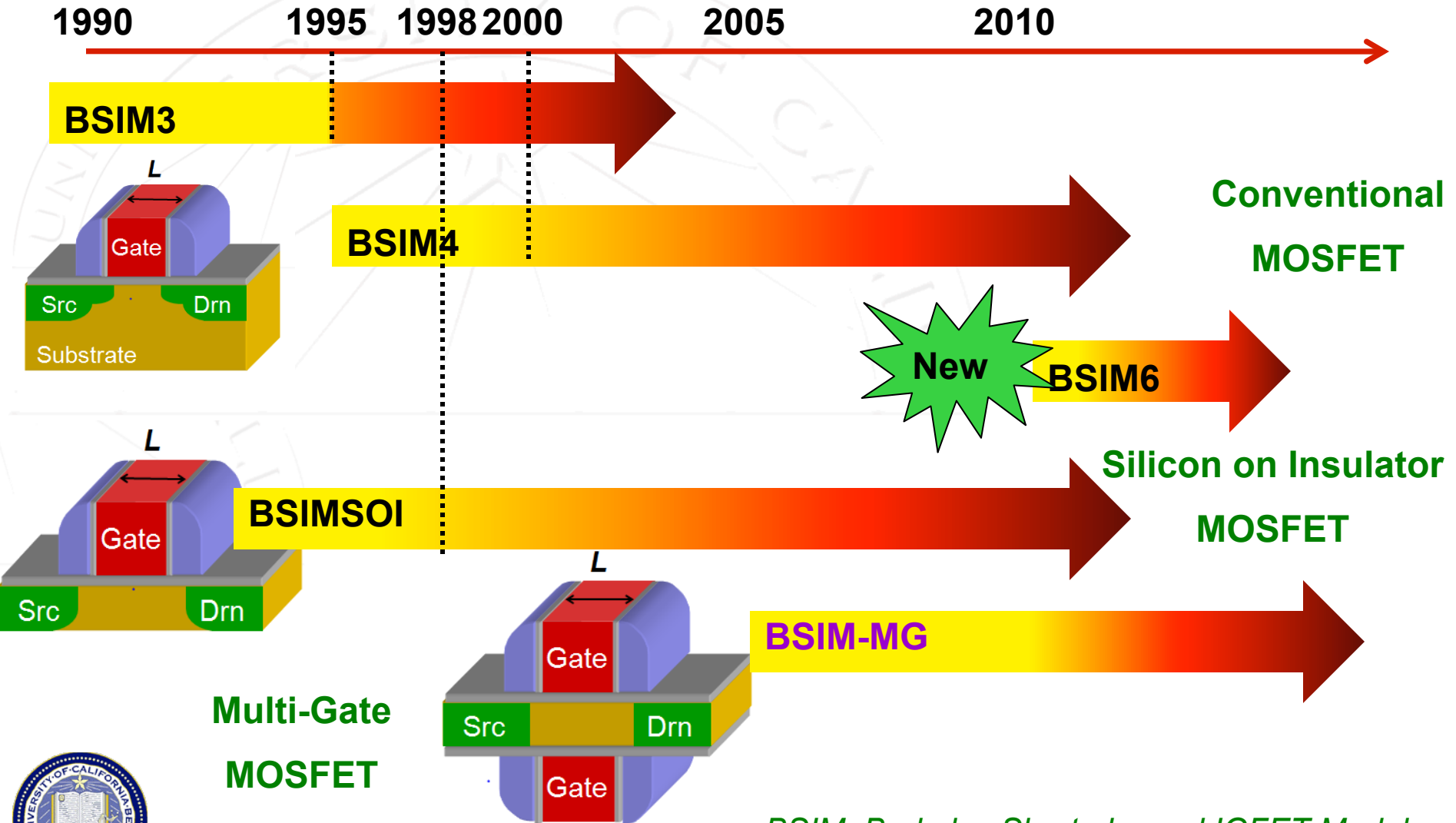
- **Excellent Convergence**

- **Example: BSIM4**

- 25,000 lines of C code
- 200+ parameters
- Open-source software implemented in all EDA tools



BSIM Family of Compact Device Models



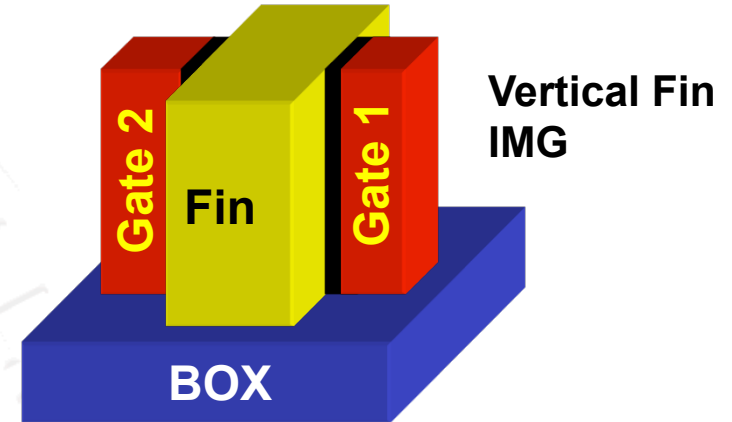
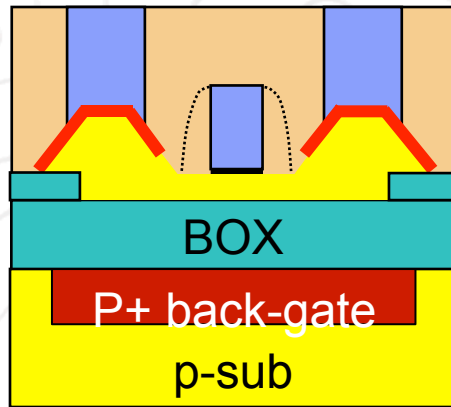
BSIM: Berkeley Short-channel IGFET Model



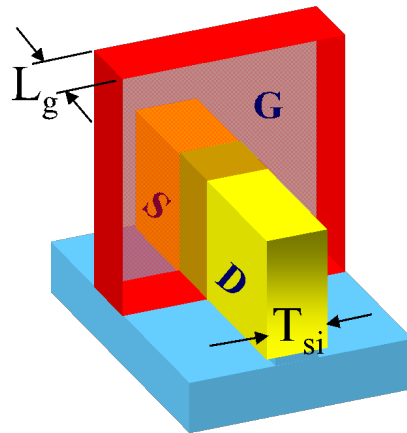
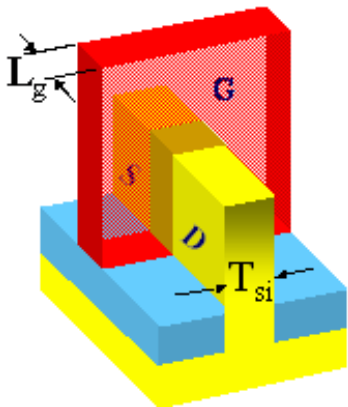
Versatile Multi-Gate Compact Model: **BSIM-MG**

BSIM-IMG

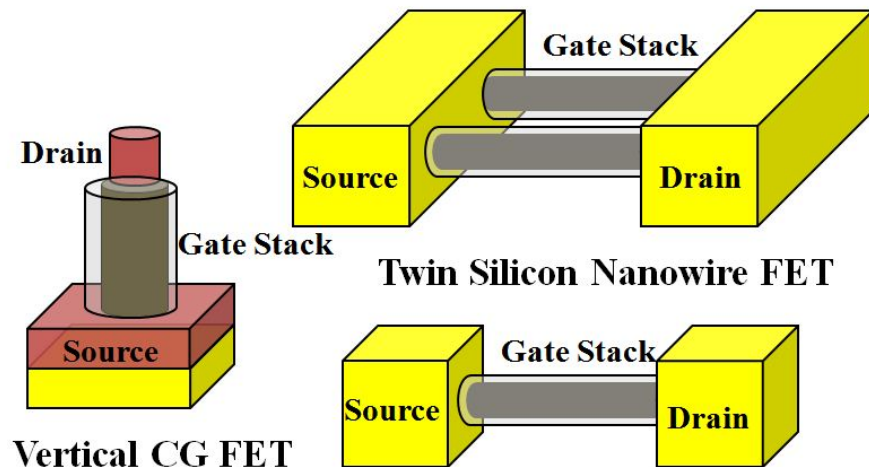
UTBSOI
BG-ETSOI



BSIM-CMG



FinFETs on Bulk and SOI Substrates



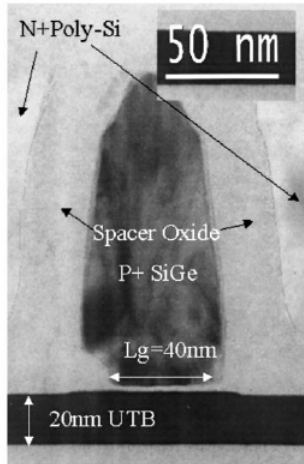
Vertical CG FET

Twin Silicon Nanowire FET

Horizontal Nanowire FET



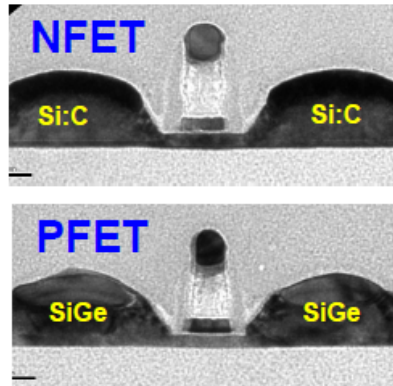
Thin-body SOI Devices



UTBSOI

Y. Choi et al.
EDL 2000

(UC Berkeley)



ETSOI

K. Cheng et al.
IEDM 2009

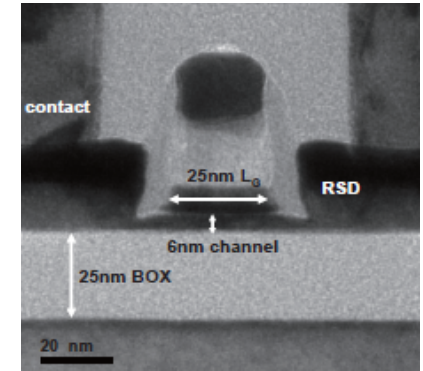
(IBM)



UT2B

F. Andrieu et al.
VLSI 2010

(CEA-LETI)



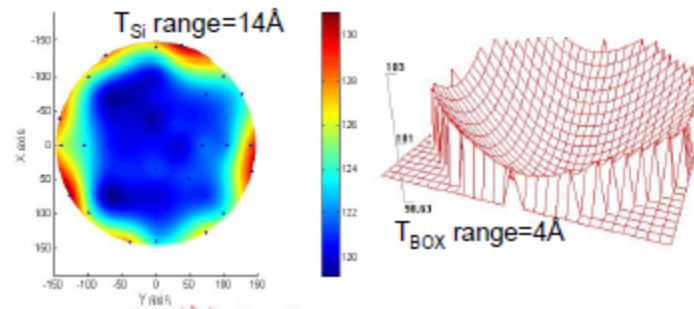
UTBB

Q. Liu et al.
VLSI 2011

(ST)

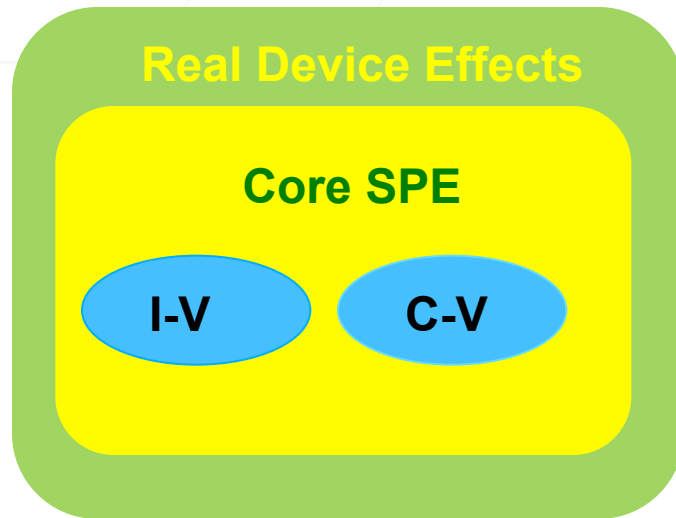
Wafer Uniformity (SOITEC):

F. Andrieu et al.,
VLSI 2010

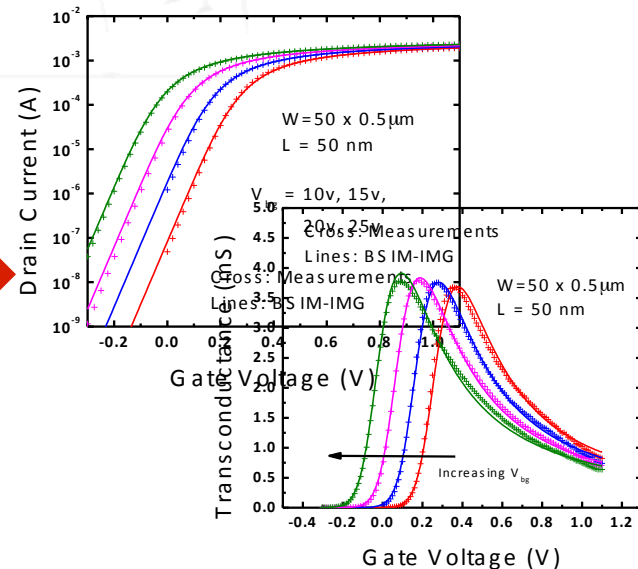


Executive Summary/ Outline : BSIM-IMG

- Production Ready Compact Model for FDSOI
- Physical Core Model
- Palette of Real Device Effects
- Validated to Hardware Silicon Data
- Synchronized with EDA Vendors Tools



BSIM-IMG



Validation



Outline

- **Introduction**
- **Core Model**
 - **Surface Potential Equation**
 - **Drain Current**
 - **Capacitance Model**
- **Real Device Effects**
- **Model Validation & QA**
- **Future Research**
- **Conclusion**



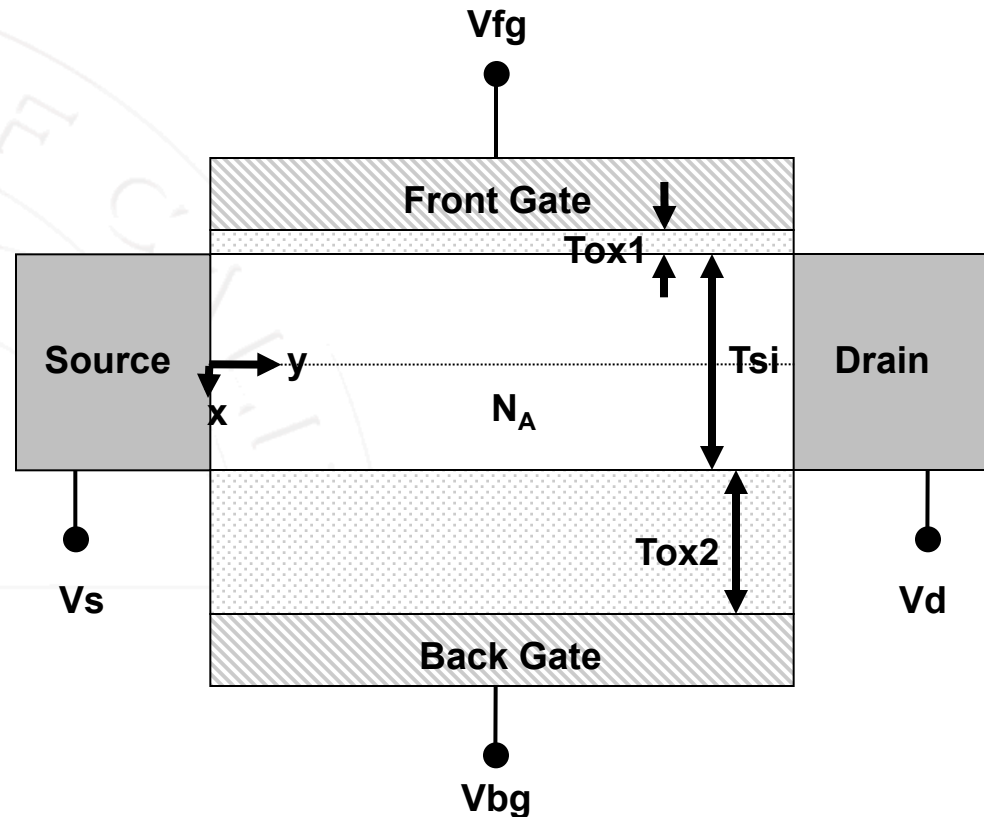
Independent-gate Device Structure: BSIM-IMG

■ Asymmetric structure

- Different Gate Work-functions
- Allows dissimilar Gate Potentials
- Different Oxide thickness and Material !

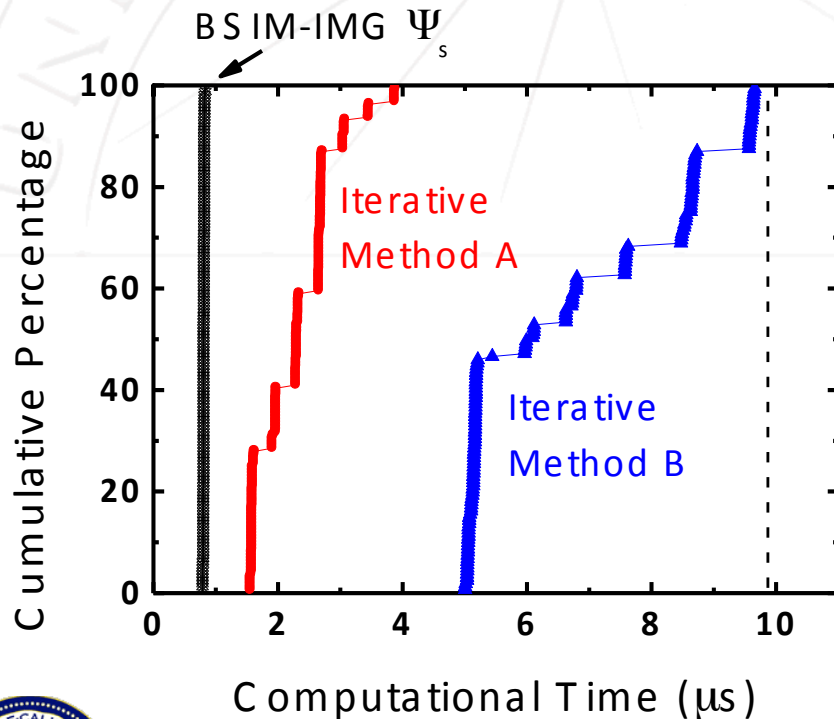
■ Captures important features

- Threshold Voltage tuning through Back-Gate
- Multi- V_{th} technology



Computationally Efficient Core

Fast!



- Efficient **Non-iterative** Surface Potential calculation
 - Investigated NR, Shooting Secant etc.
- Surface potential needs to be solved at least twice - Source and Drain side
 - Obtain ψ_s / Q_{is} and ψ_d / Q_{id}



D. Lu et al., SSE 2011

Surface Potential Derivation

- Quasi-Fermi level at the source is taken as a reference for the potential (ψ).

$$\psi = -\frac{E_c - E_f(\text{source})}{q}$$

- Start from the Poisson's equation

$$\epsilon_{si} \frac{d^2 \psi(x, y)}{dx^2} = qN_c \exp\left(\frac{q(\psi(x, y) - V_{ch}(y))}{kT}\right)$$

- The continuity of displacement field at the front and back interfaces gives the following relation of the surface electric fields ($E_{s1} = -\left.\frac{d\psi}{dx}\right|_{x=-T_{si}/2}$ and $E_{s2} = -\left.\frac{d\psi}{dx}\right|_{x=T_{si}/2}$) and surface potentials:

$$C_{ox1(2)}(V_{fg(bg)} - \Delta\Phi_{1(2)} - \psi_{s1(2)}) = \epsilon_{si} E_{s1(2)}$$



Surface Potential Derivation (Contd.)

- Multiplying both sides of Poisson's Eq. by $\frac{d\psi}{dx}$ and integrating yields

$$E_{s1}^2 - E_{s2}^2 = \frac{2qN_c V_{th}}{\epsilon_{si}} \left\{ \exp\left(\frac{\psi_{s1} - V_{ch}}{V_{th}}\right) - \exp\left(\frac{\psi_{s2} - V_{ch}}{V_{th}}\right) \right\}$$

- Replacing E_{s1} with ψ_{s1}

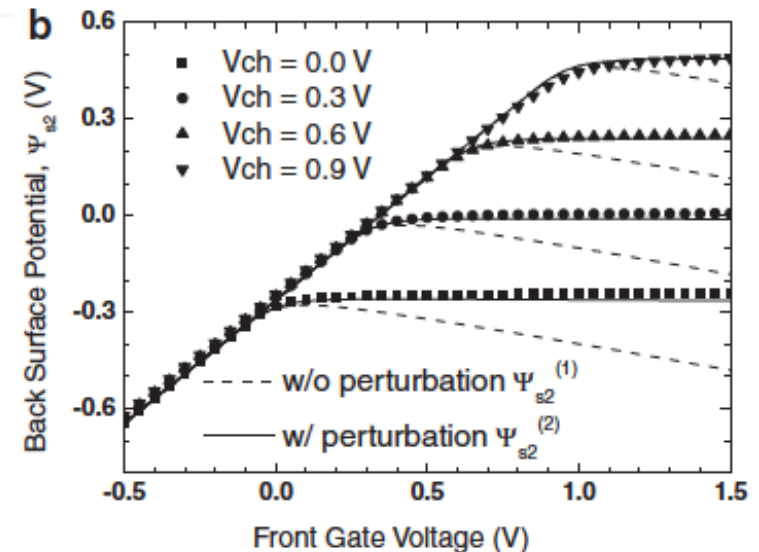
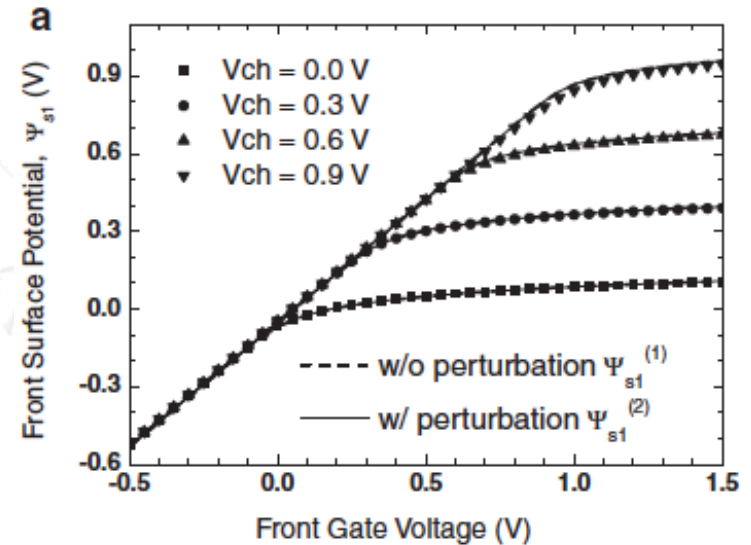
$$\left(\frac{C_{ox1}(V_{fg} - \Delta\Phi_1 - \psi_{s1})}{\epsilon_{si}}\right)^2 - E_{s2}^2 = \frac{2N_c kT}{\epsilon_{si}} \exp\left(\frac{q(\psi_{s1} - V_{ch})}{kT}\right)$$

- E_{s2} approximation

$$E_{s2} = \frac{(V_{fg} - \Delta\Phi_1) - (V_{bg} - \Delta\Phi_2)}{\frac{\epsilon_{si}}{\epsilon_{ox}}(T_{ox1} + T_{ox2}) + T_{si}}$$

- Using perturbation to improve accuracy at strong inversion

$$E'_{s2} = \frac{\psi_{s1}^{(1)} - (V_{bg} - \Delta\Phi_2)}{\frac{\epsilon_{si}}{\epsilon_{ox}}T_{ox2} + T_{si}}$$



Relating ψ_{s2} with ψ_{s1}

Generalization of Poisson's equation

$$\left(\frac{d\psi}{dx}\right)^2 - A \cdot \exp\left(\frac{q(\psi - V_{ch})}{kT}\right) = D$$

$D < 0$

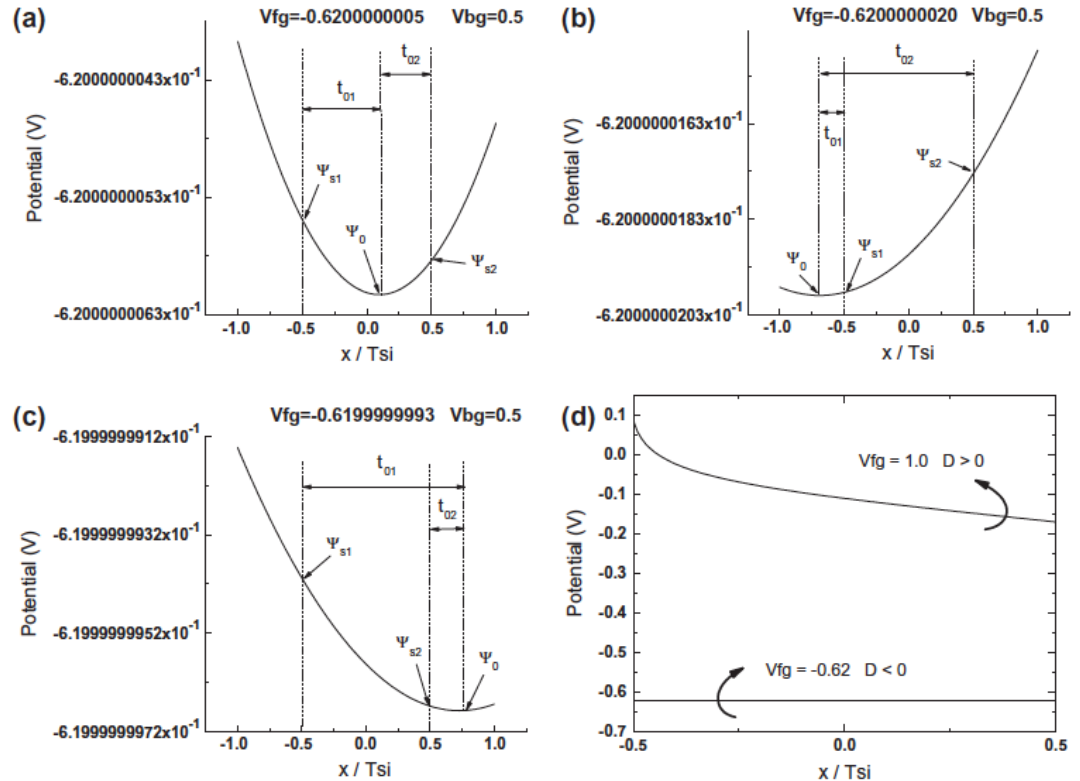
$$t_{01} = \left| \left(\frac{2kT}{q\sqrt{-D}} \right) \cos^{-1} \left[\sqrt{-\frac{D}{A} \exp\left(-\frac{q(\psi_{s1} - V_{ch})}{kT}\right)} \right] \right|$$

$$t_{02} = \begin{cases} |T_{si} - t_{01}| & E_{s1} > 0 \\ T_{si} + t_{01} & E_{s1} < 0 \end{cases}$$

$$\psi_{s2} = V_{ch} - \frac{kT}{q} \ln \left\{ \frac{A}{-D} \cos^2 \left[\left(\frac{q\sqrt{-D}}{2kT} \right) t_{02} \right] \right\}$$

$$E_{s2} = -\frac{\partial\psi_{s2}}{\partial t_{02}}$$

$$Q_{inv} = \varepsilon_s (E_{s1} - E_{s2})$$



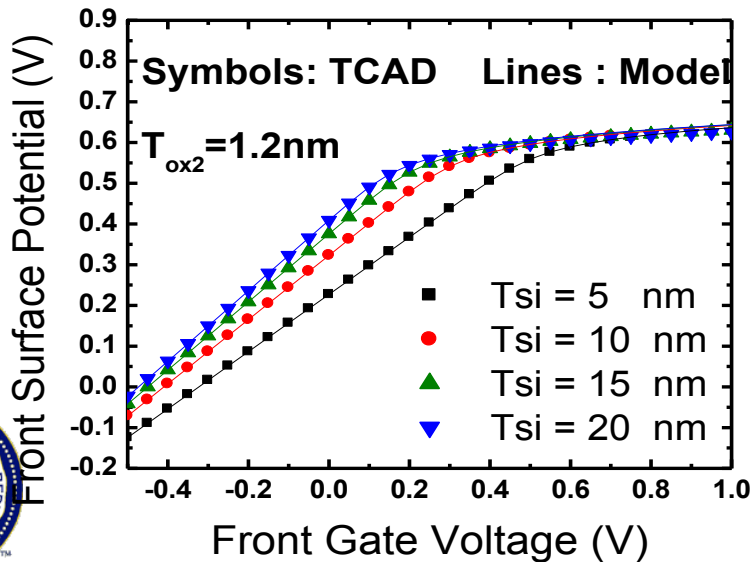
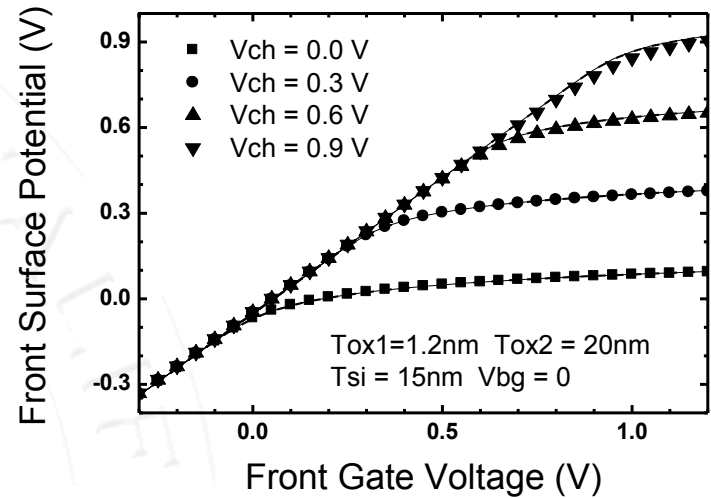
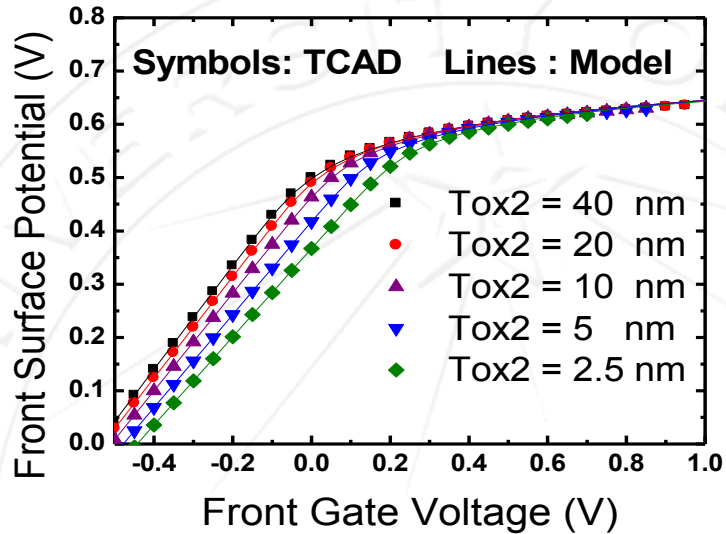
$D > 0$

$$\psi_{s2} = V_{ch} + \frac{kT}{q} \ln \left[\frac{D}{A} \left(\frac{2C}{1 - C^2} \right)^2 \right]$$

$$C = \left[\sqrt{\frac{D}{A} \exp\left(-\frac{q(\psi_{s1} - V_{ch})}{kT}\right)} + 1 - \sqrt{\frac{D}{A} \exp\left(-\frac{q(\psi_{s1} - V_{ch})}{kT}\right)} \right] \times \exp \left[-\text{sgn}(E_{s1}) \frac{q\sqrt{D}}{2kT} T_{si} \right]$$



Surface Potential: Verification with TCAD



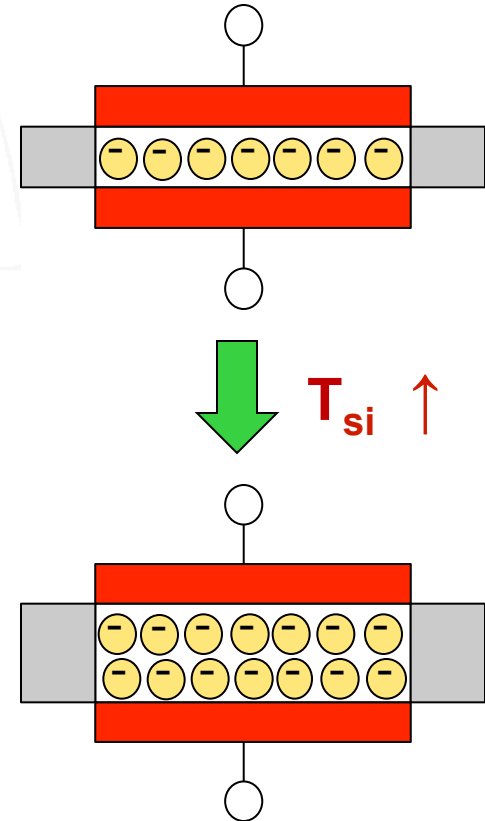
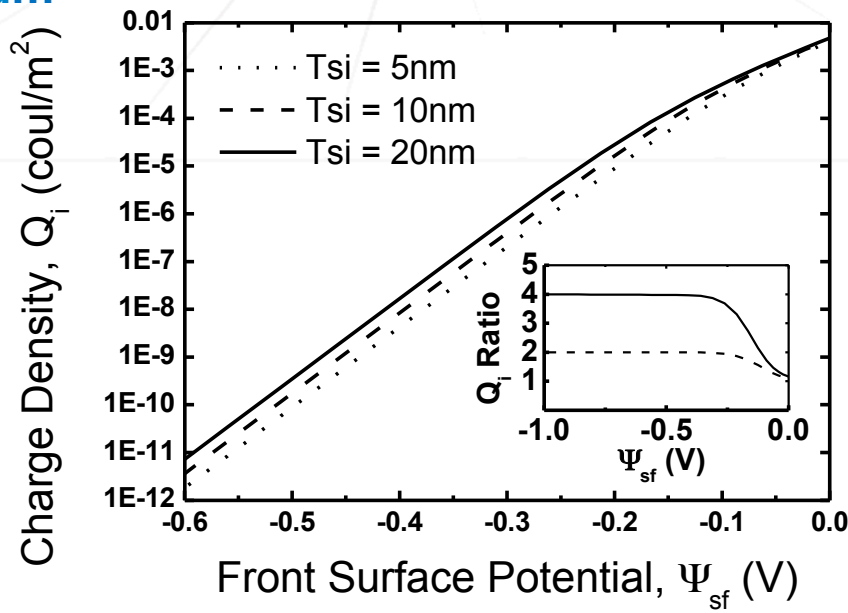
Scalable w.r.t. physical parameters like T_{si} , T_{ox} (front and back) and node voltages etc.



Volume Inversion

- **Preserves Important Property** like Volume Inversion
 - In sub-threshold (Low field), the charge density Q_i is proportional to the body thickness T_{si}

$T_{oxb} = 10\mu\text{m}$



Drain Current Model

■ Drain Current

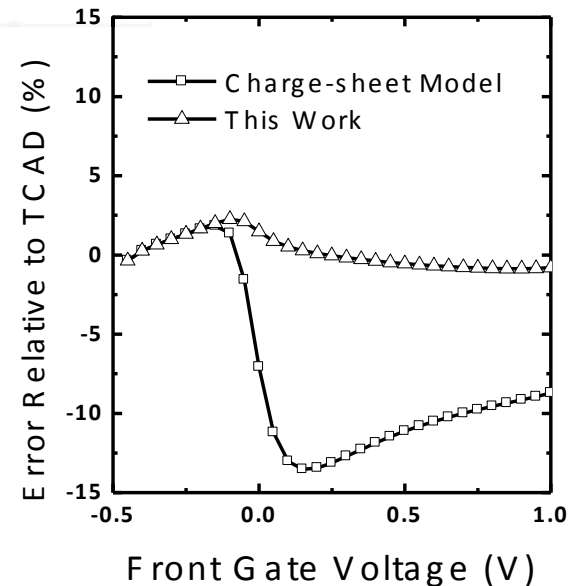
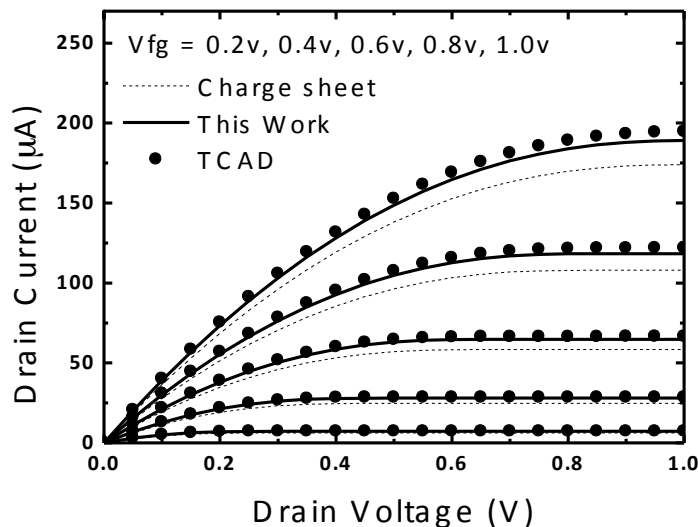
$$I_{ds} = \mu \cdot \frac{W}{L} \cdot \left[\underbrace{\frac{Q_{inv,s} + Q_{inv,d}}{2} (\psi_{s1,d} - \psi_{s1,s})}_{\text{Drift}} + \underbrace{\eta \cdot \frac{kT}{q} (Q_{inv,s} - Q_{inv,d})}_{\text{Diffusion}} \right]$$

$$\eta = 2 - \frac{2\epsilon_{si} \bar{E}_{s2}}{Q_{inv} + 2\epsilon_{si} \bar{E}_{s2}}$$

Q_{inv} : inversion carrier density
 E_{s2} : back-side electric field
 ψ_{s1} : front-side surface potential

No Charge-sheet Approximation

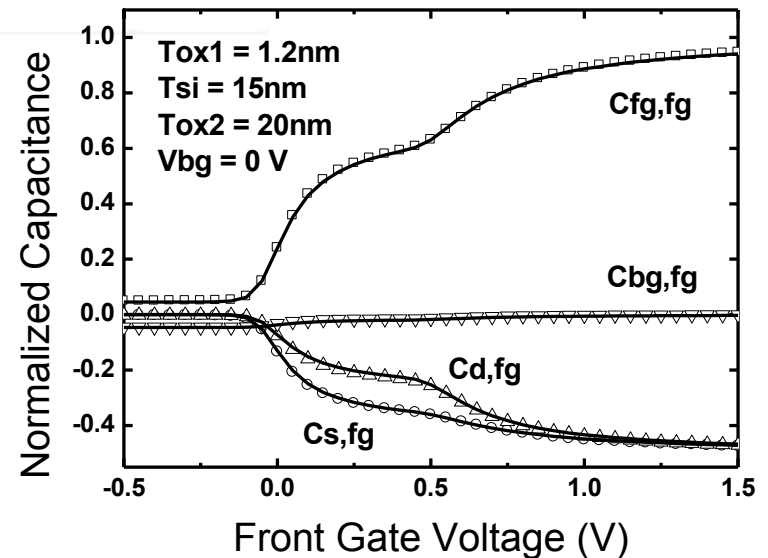
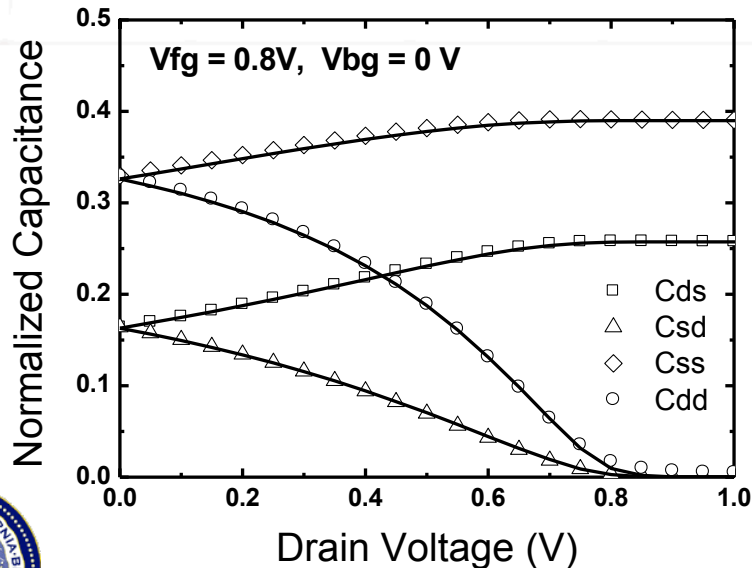
Very high accuracy



Capacitance Model

- Model inherently exhibits **symmetry**
 - $C_{ij} = C_{ji}$ @ $V_{ds} = 0$ V
- Model overlays TCAD results
 - No tuning parameters used

$T_{oxf} = 1.2\text{nm}$, $T_{oxb} = 20\text{nm}$,
 $T_{si} = 15\text{nm}$, $V_{bg} = 0$ V

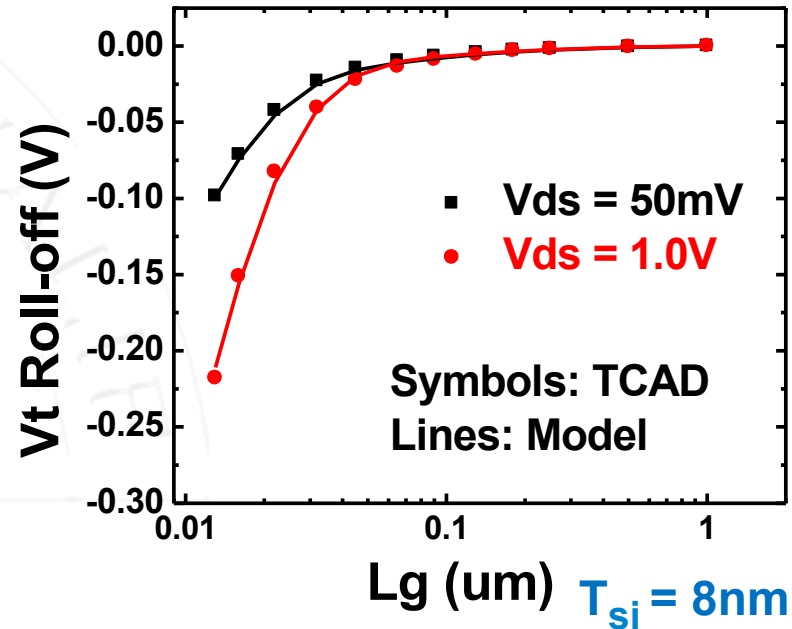
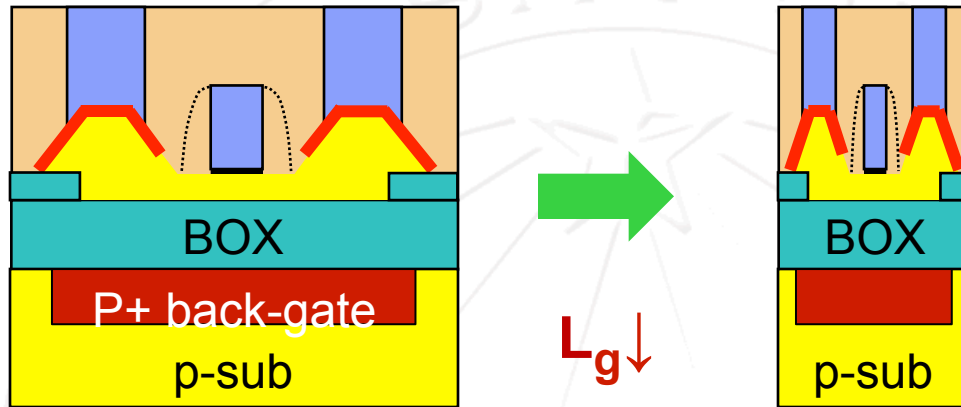


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Short Channel Effects



$$\Delta V_{th} = \frac{0.5 \cdot DVT0}{\cosh\left(DVT1 \cdot \frac{L}{\lambda}\right)} \times (V_{bi} - \phi_s) + \frac{0.5 \cdot ETA0}{\cosh\left(DSUB \cdot \frac{L}{\lambda}\right)} \times V_{ds}$$

Scale Length

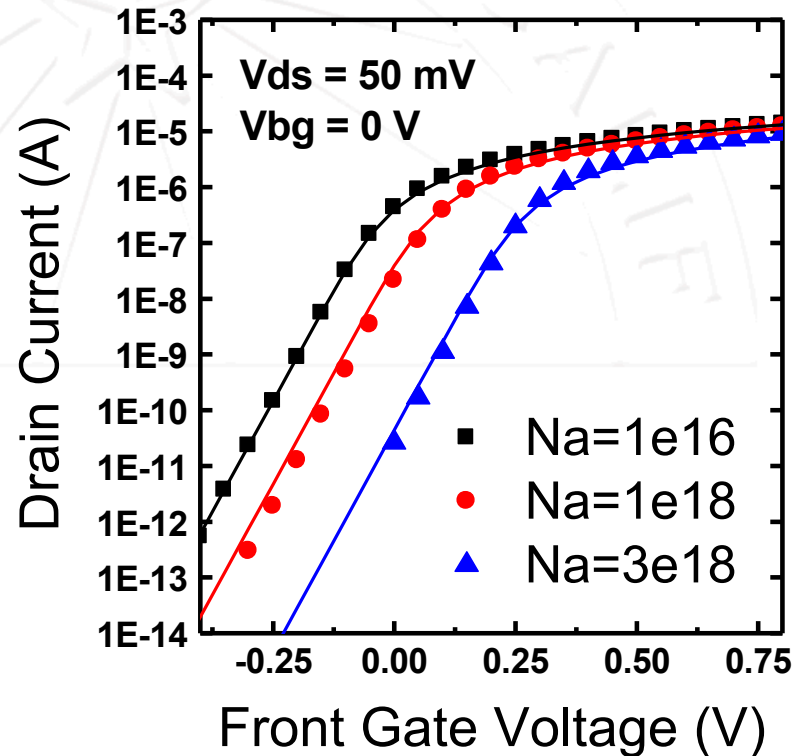
$$\lambda = \sqrt{\frac{\epsilon_{si}}{2\epsilon_{ox}} \cdot T_{si} \cdot T_{ox1} \cdot \left[1 + \frac{T_{ox2} - T_{ox1}}{T_{ox1} + T_{ox2} + T_{si} \cdot \frac{\epsilon_{ox}}{\epsilon_{si}}} \right]}$$

$T_{si} = 8\text{nm}$
 $T_{box} = 4\text{nm}$



Doping Dependence

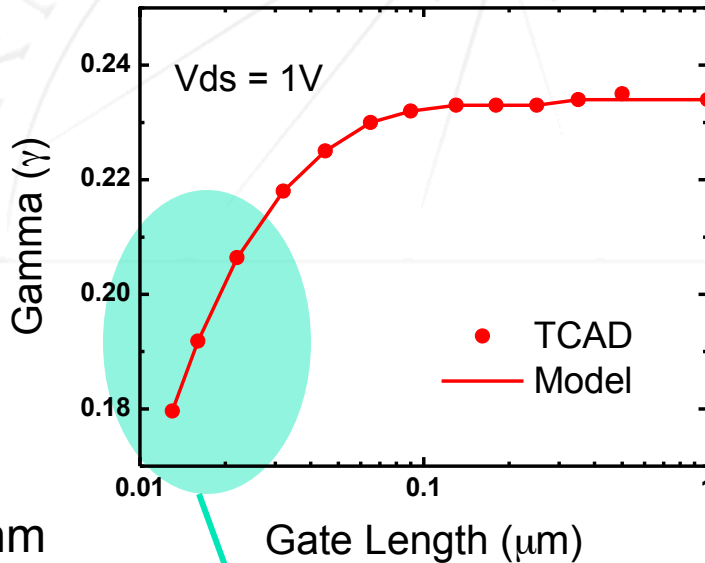
- Threshold voltage shift as function of doping is captured



Length Dependent γ Model

- Capacitive coupling ratio

$$\gamma = -\frac{dV_{TH}}{dV_{bg}}$$

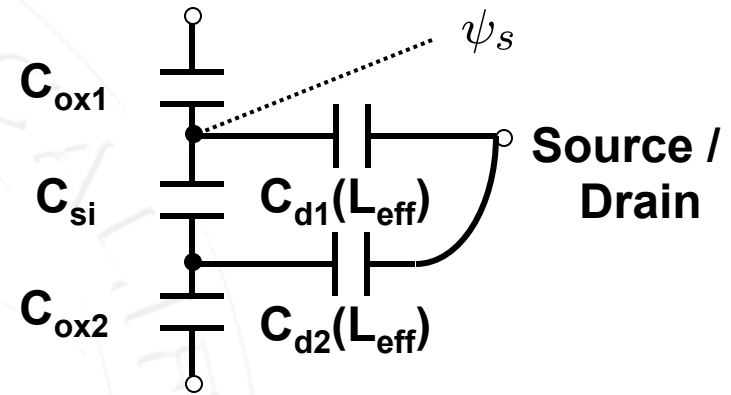


$T_{si} = 8\text{nm}$

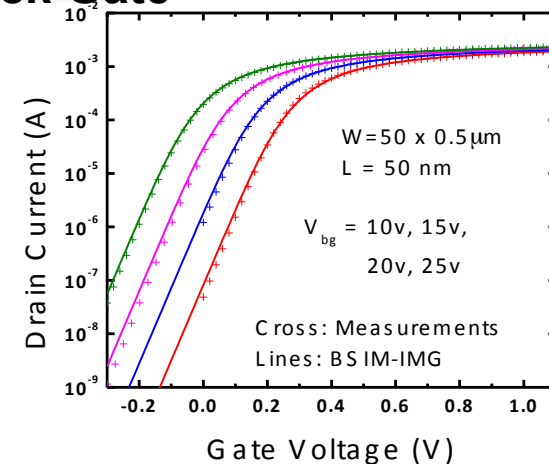
$T_{box} = 4\text{nm}$

γ degraded at short channel

Front Gate



Back Gate



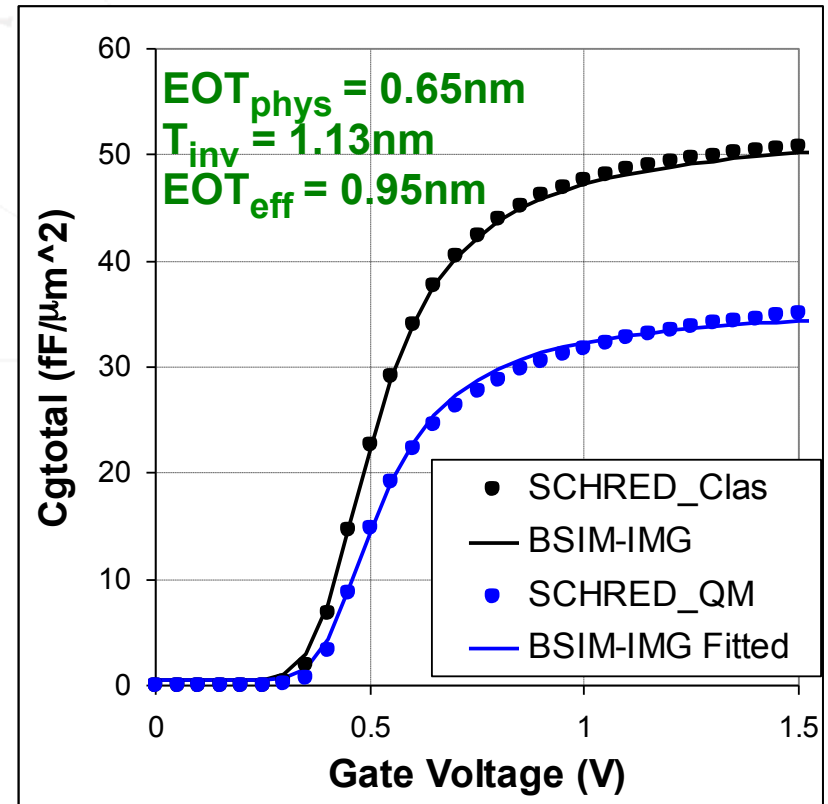
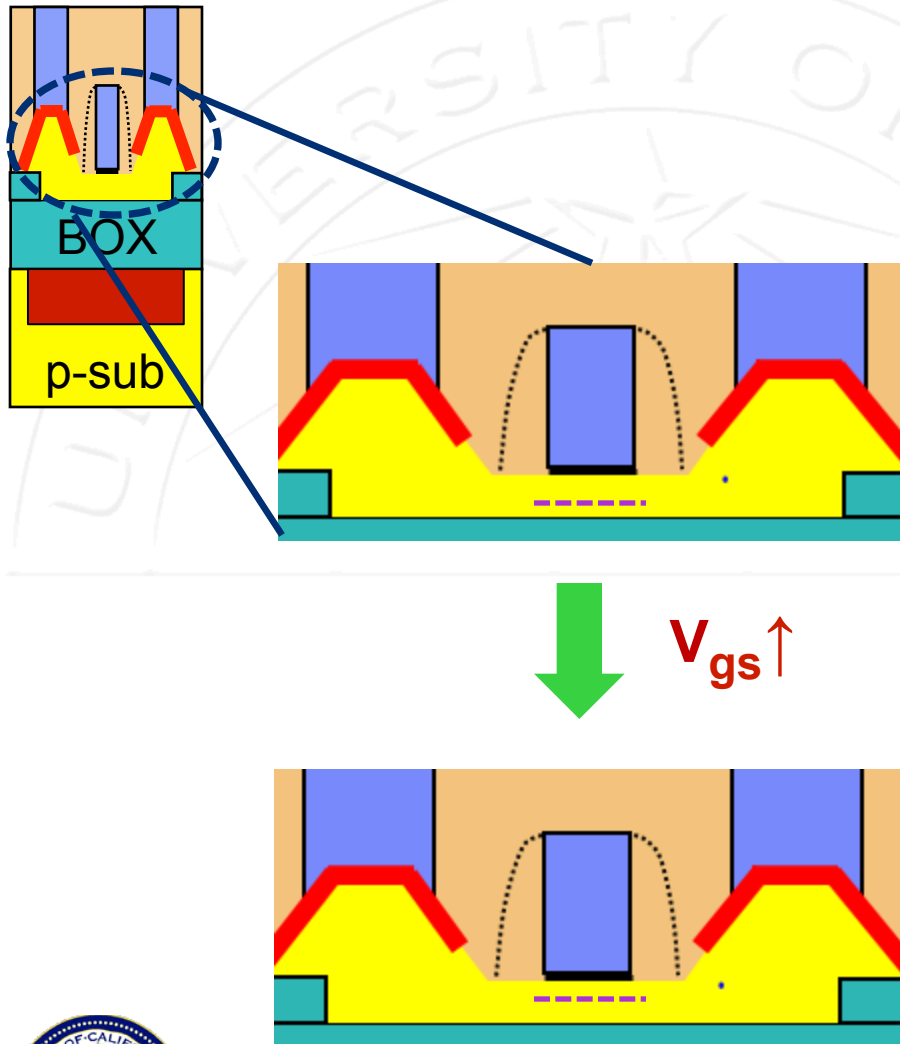
Captures V_{bg} effect in I-V



QM Effect: Inv. Charge Centroid Model

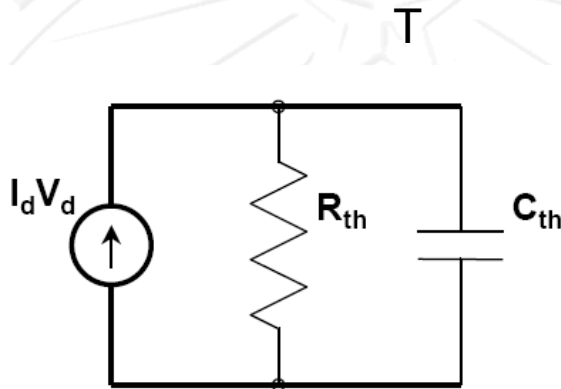
$$V_{dd} = 0.9 \text{ V} ; V_{fb} = 28 \text{ mV}$$

$$T_{BOX} = 140 \text{ nm} ; T_{si} = 6 \text{ nm} ; N_{sub} = 1 \text{e}16 \text{ cm}^{-3}$$



Self Heating Model

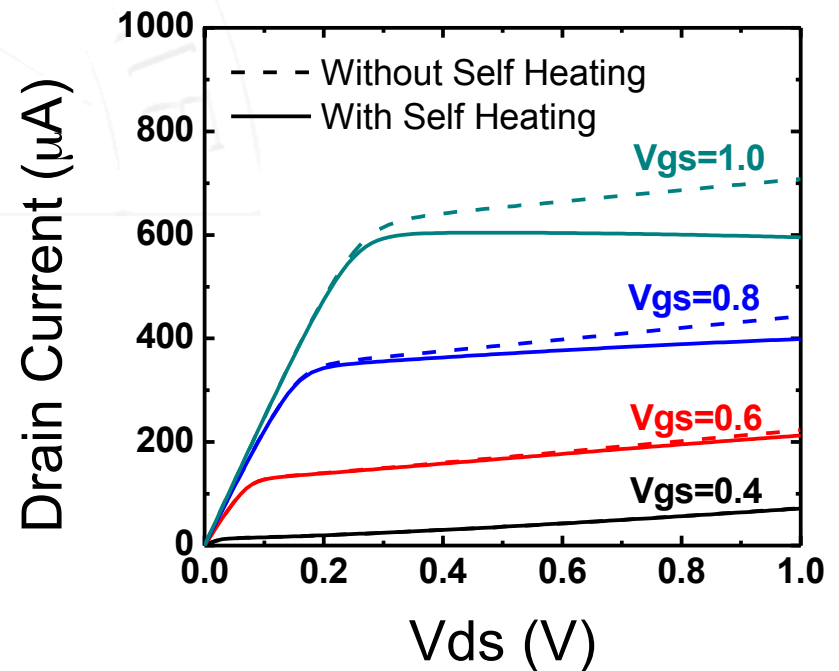
- **Thermal Node:** R_{th}/C_{th} methodology



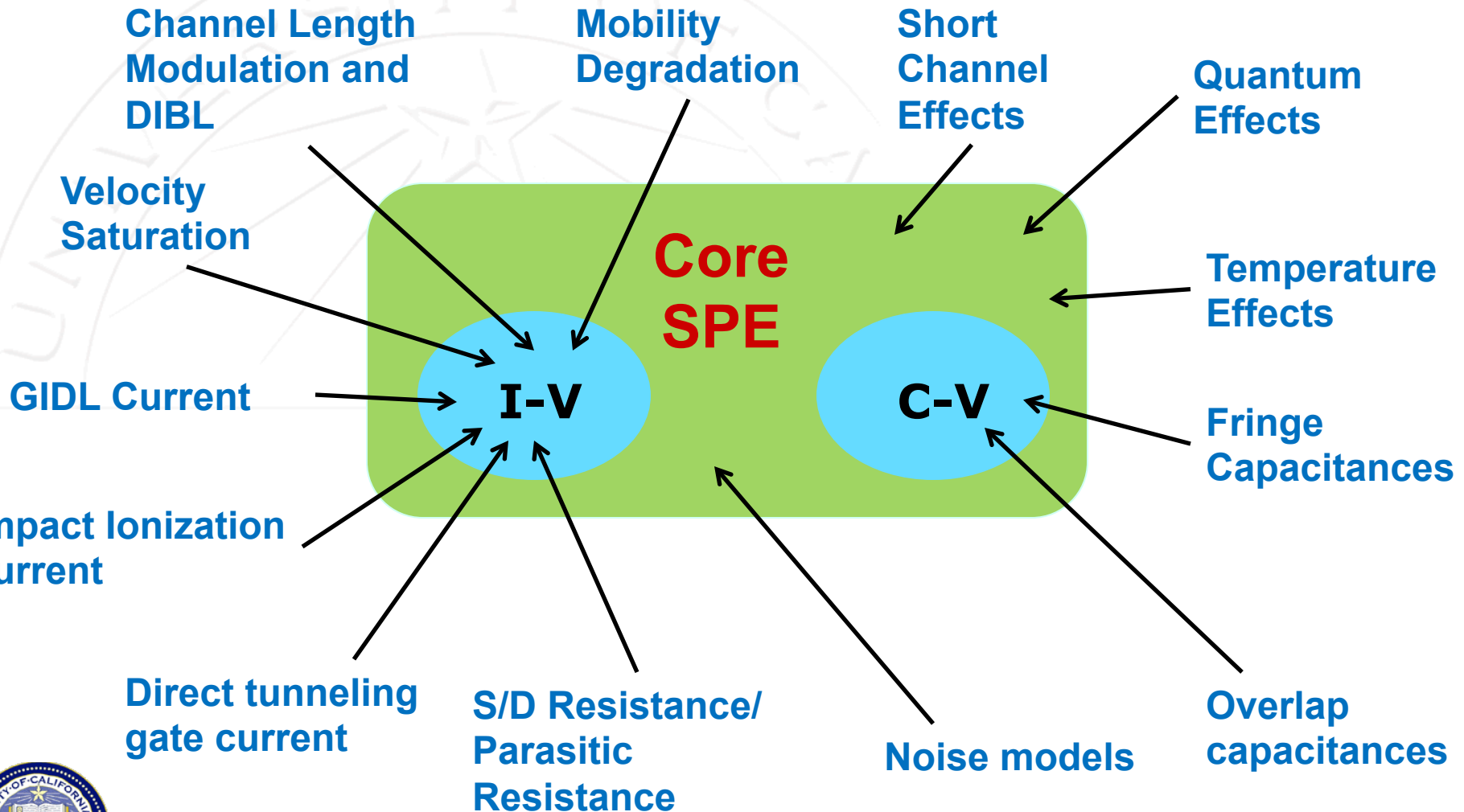
- Relies on **Accurate** physical modeling of **Temperature Effects** in the model

$$R_{th} = \frac{R_{THO}}{W_{THO} + W_{eff}}$$

$$C_{th} = C_{THO} \cdot (W_{THO} + W_{eff})$$



Real Device Effects



More Effects?



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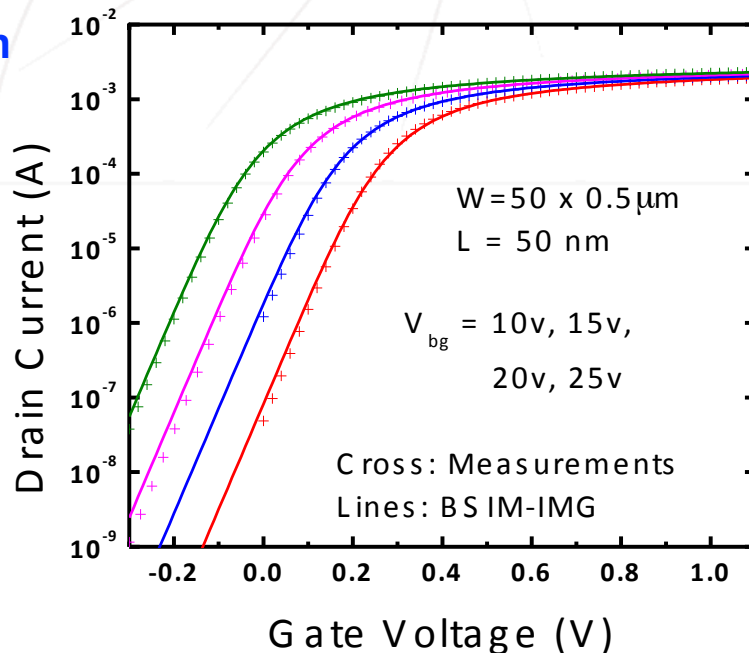


Validation to Hardware Data

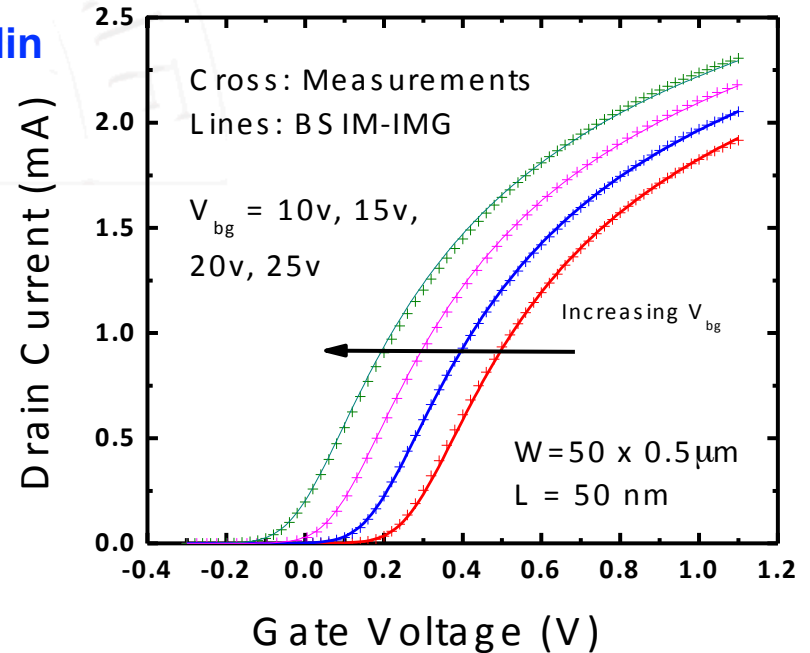
Device from CEA-LETI

- $T_{\text{box}} = 145\text{nm}$ $EOT = 1.6\text{nm}$ $T_{\text{si}} = 8\text{nm}$ $W = 0.5\mu\text{m} \times 50$
 $L = 50\text{nm}$ $N_a = 1e15$ $\Phi_{g2} = 5.0$ $\Phi_{g1} = 4.55$ (fitted)
- $V_{\text{bg}} = \text{floating}, 10\text{V}, 15\text{V}, 20\text{V}, 25\text{V}$

$I_{d,\text{lin}}$

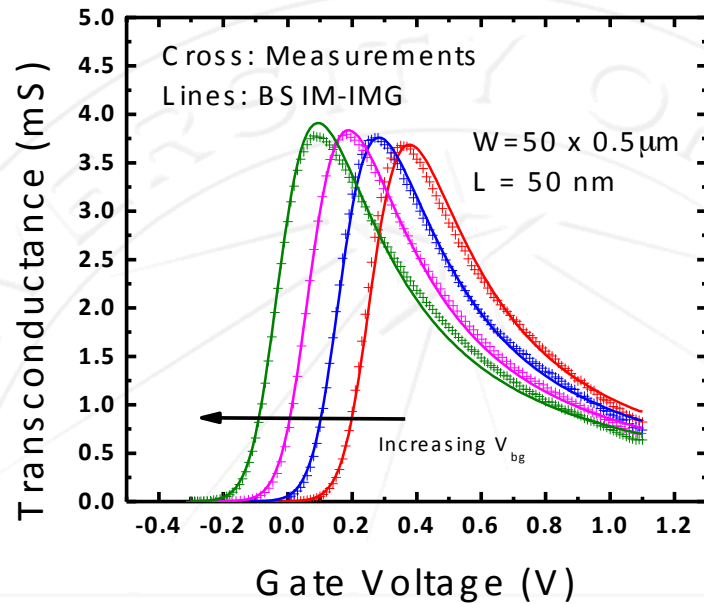


$I_{d,\text{lin}}$

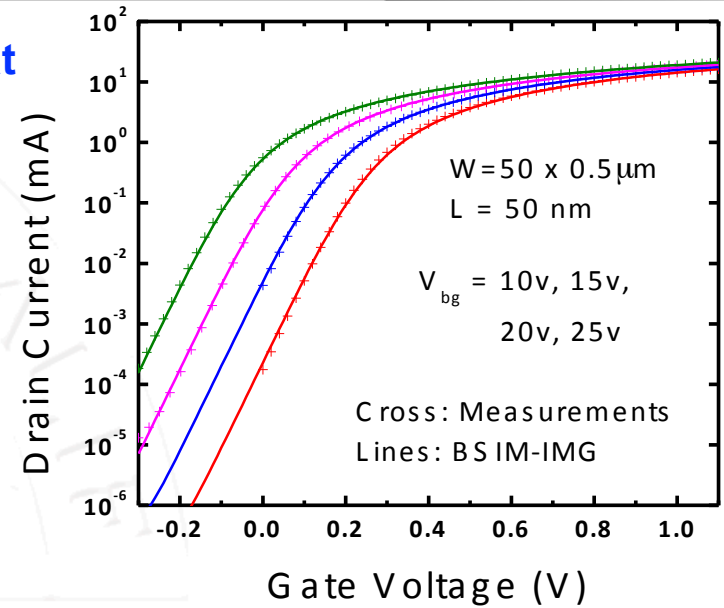


Validation Contd.

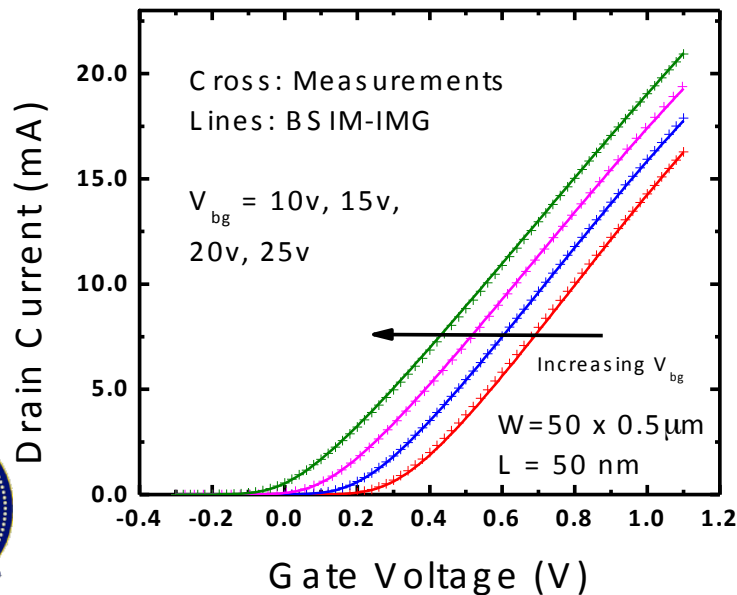
$G_{m,lin}$



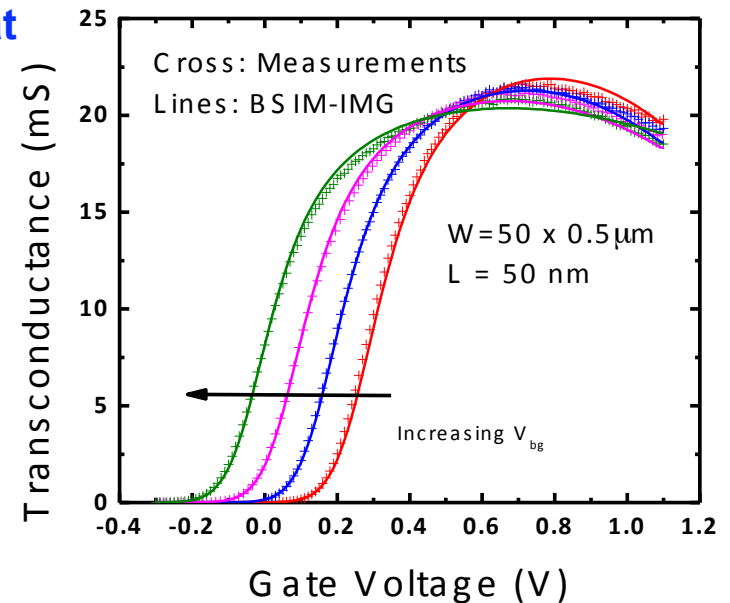
$I_{d,sat}$



$I_{d,sat}$



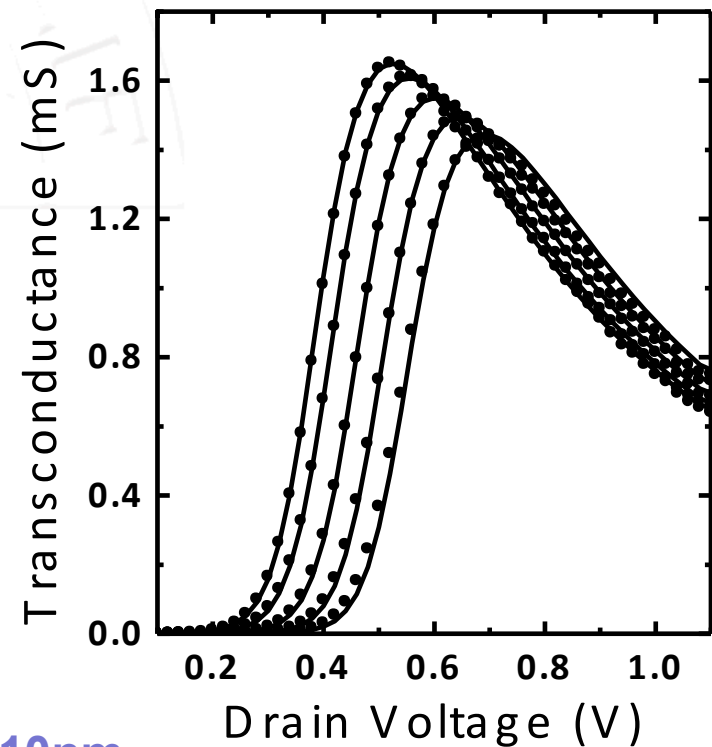
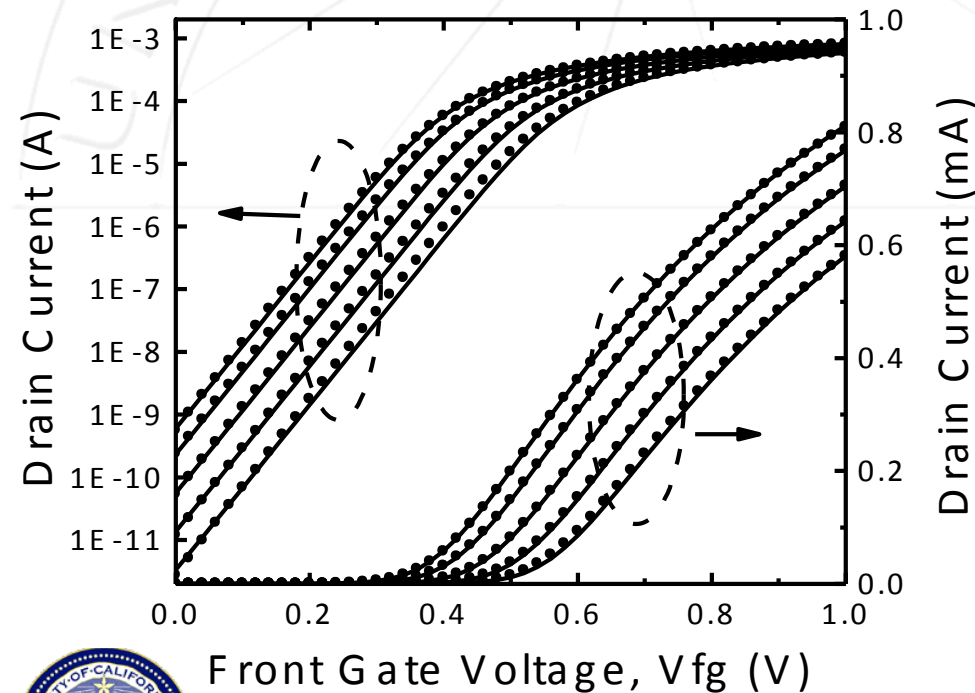
$G_{m,sat}$



Extraction Results : I_d - V_{fg} and G_m - V_{fg} with varying V_{bg}

- I_d - V_{fg} with varying back bias
 - $V_{bg}=0, -0.2, -0.5, -0.8, -1.1$ V
 - $V_{ds}=50$ mV

- Transconductance (G_m)

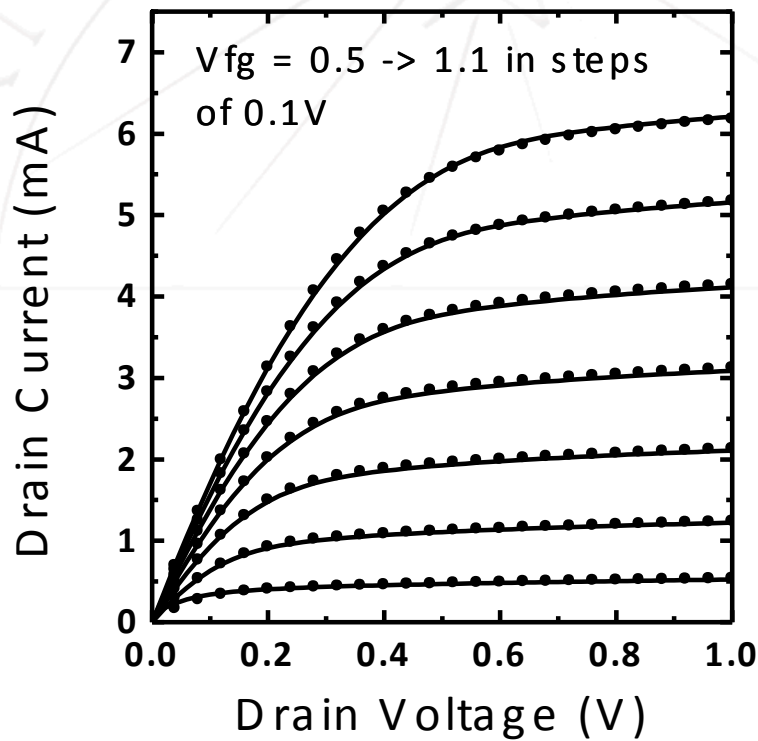


$L_g=30$ nm $TBOX=10$ nm

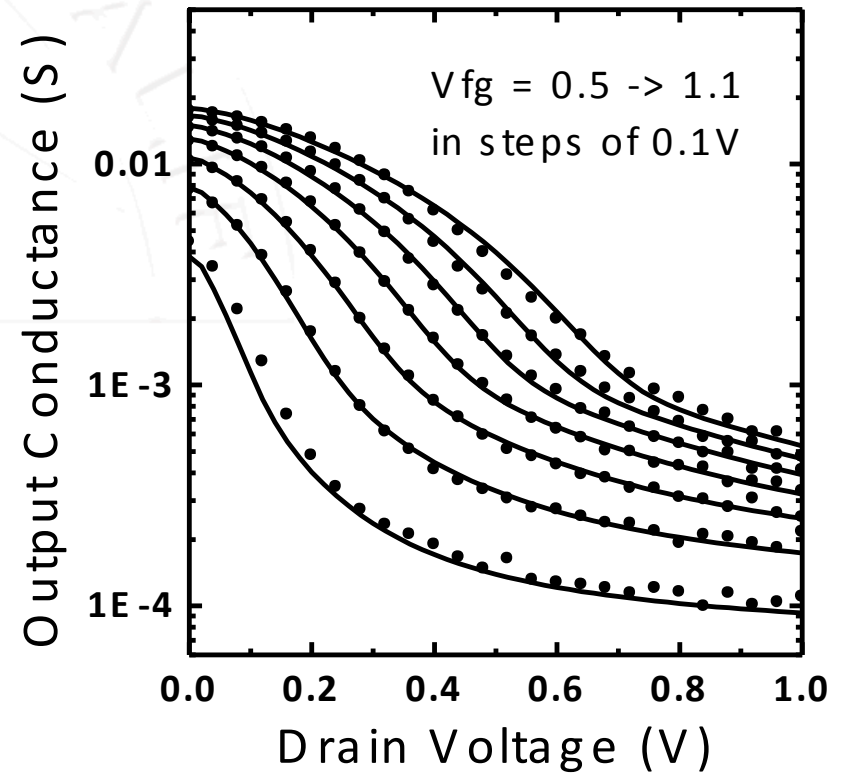


Extraction Results : I_d - V_{ds} and G_{ds} - V_{ds} with varying V_{bg}

- I_d - V_{ds} at $V_{fg}=0.5, 0.6, 0.7, 0.8, 0.9, 1.0, 1.1$ V



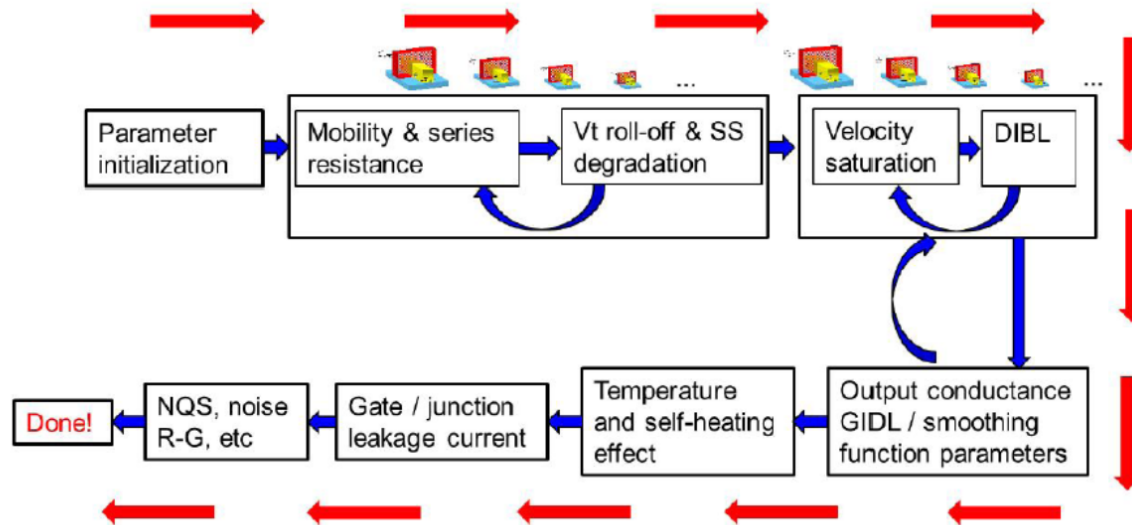
- Output Conductance (G_{ds})



$L_g=30\text{nm}$, $TBOX=10\text{nm}$



Global Parameter Extraction for ETSOI



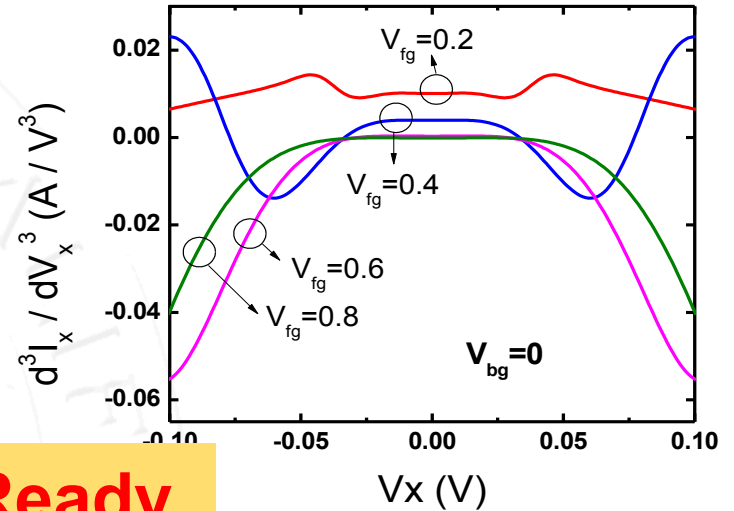
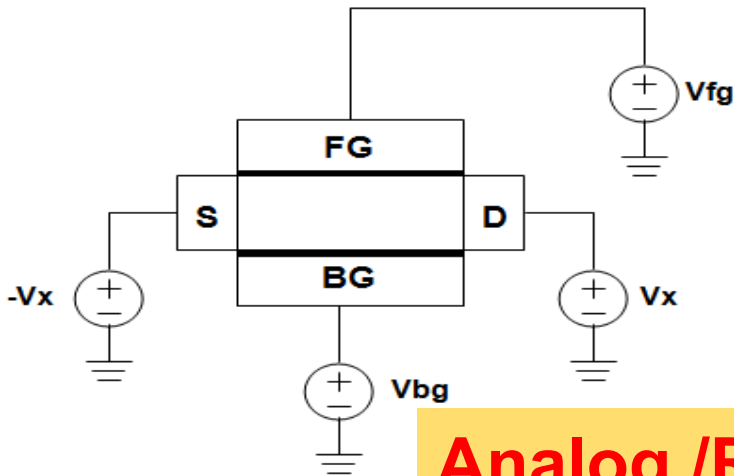
■ Calibration of the model

- Through internship **at IBM T.J. Watson**
 - Work by Darsen Lu
- Global Extraction performed for NMOS & PMOS at L=24nm 66nm
- **Excellent agreement** for I-V across all gate lengths
- C-V extracted and fine-tuned to match ring oscillator delay v.s. V_{dd}



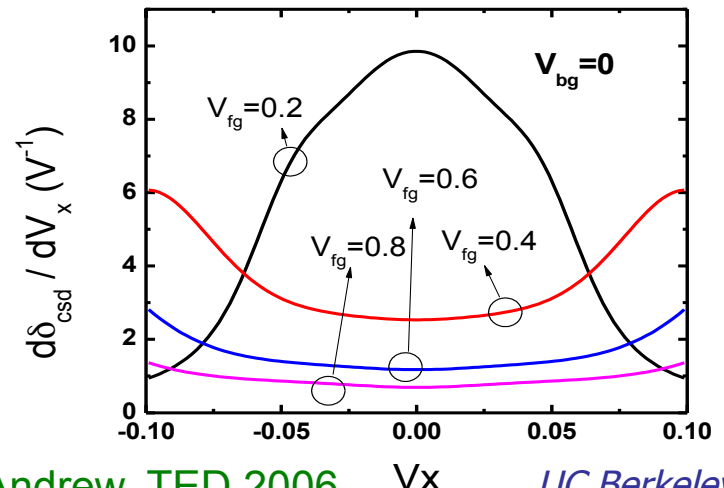
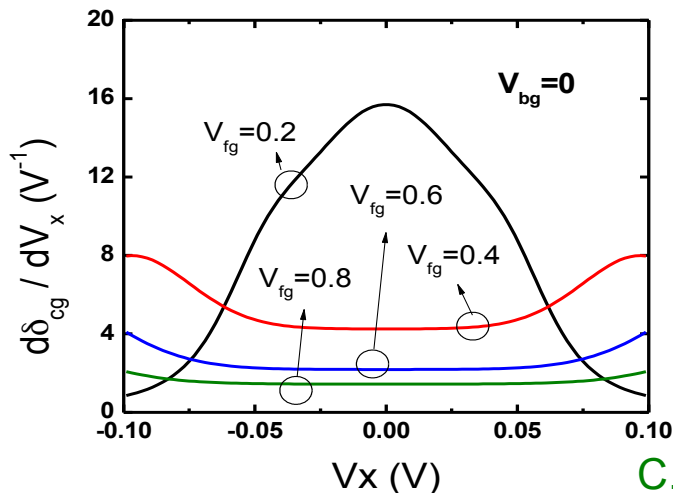
Gummel Symmetry Test

■ Drain Current Symmetry



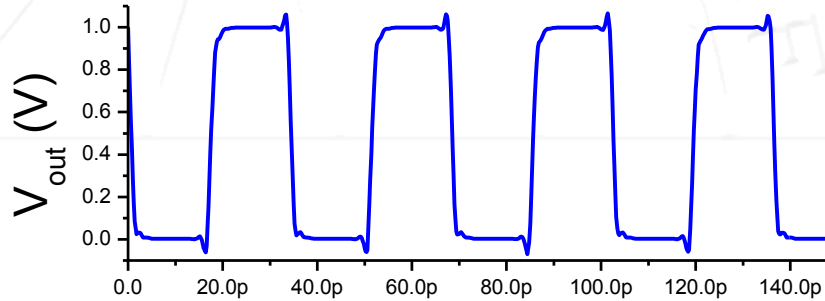
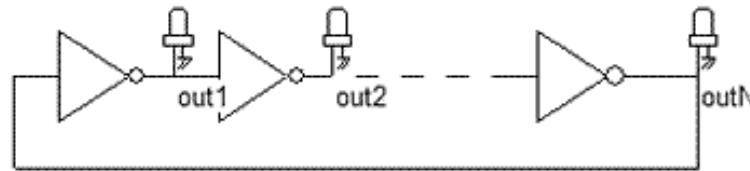
Analog /RF Ready

■ AC (charge) Symmetry



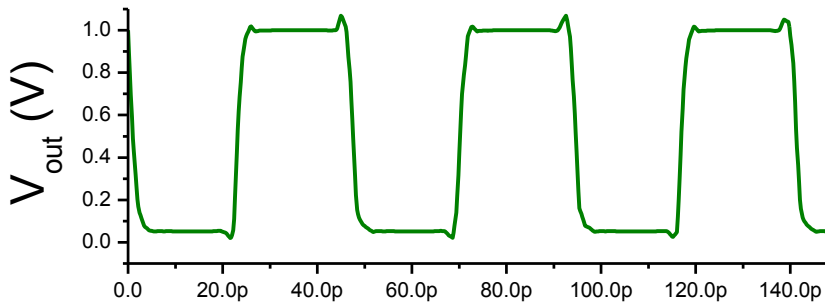
Convergence Tests

- **Excellent Convergence Properties**
- **Ex: 17-stage ring oscillator**



$$V_{bgn} = 0 \text{ V}$$

$$V_{bgp} = 1 \text{ V}$$



$$V_{bgn} = -3 \text{ V}$$

$$V_{bgp} = 4 \text{ V}$$

**Various
Back-Gate
Potential
Conditions**

Time (sec)



Speed Tests

Circuit	# MOSFETs	Model	Runtime per iteration per transistor (μs)
1-Transistor Id-Vds	1	BSIM4	40.7
		IMG	29.1
17-Stage Ring	34	BSIM4	31.3
		IMG	18.8
Coupled Rings	2020	BSIM4	41.0
		IMG	22.6

- **Speed of BSIM-IMG v101 and BSIM v4.5 compared**
 - Both model compiled with the in-built Verilog-A compiler of HSpice
 - Note: Each model uses its own default parameter. Parameters are not extracted for a real technology.
 - GIDL, I_g , Self-heating turned off.

Averaged over 5 runs on a Linux box with a single-core AMD Opteron Processor (2.39GHz)



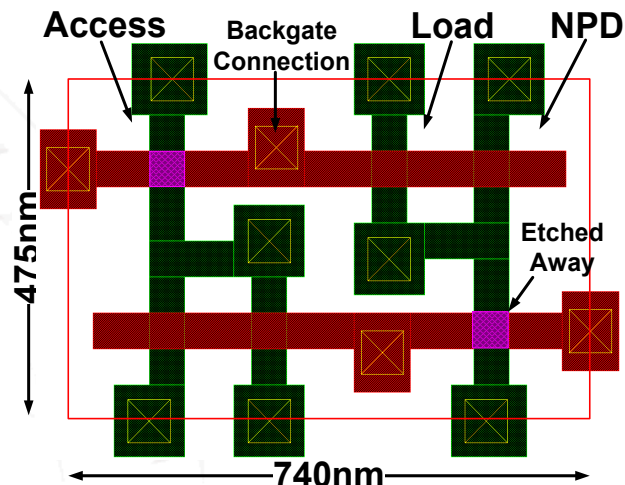
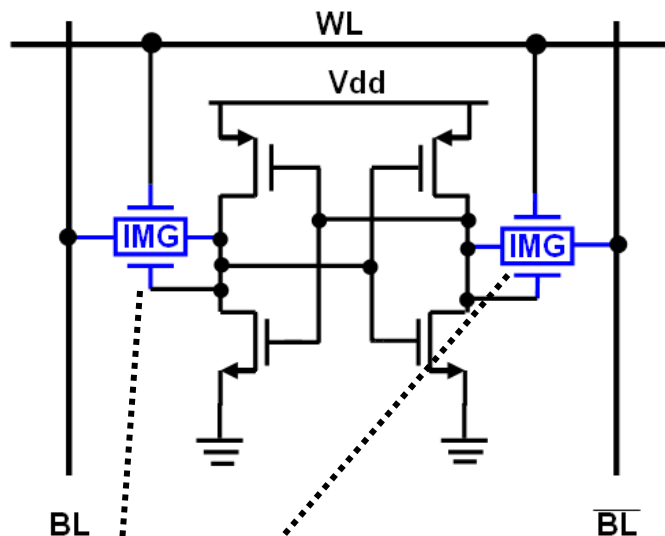
Outline

- **Introduction**
- **Core Model**
 - **Surface Potential Equation**
 - **Drain Current**
 - **Capacitance Model**
- **Real Device Effects**
- **Model Validation & QA**
- **Future Research**
- **Conclusion**



Application Example: FinFET SRAM with Back-gate Dynamic Feedback

6T SRAM Cell using FinFETs

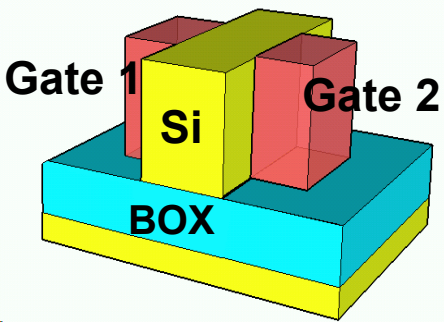


Cell Area =
0.35um²

(Courtesy of Sriram Balasubramanian)

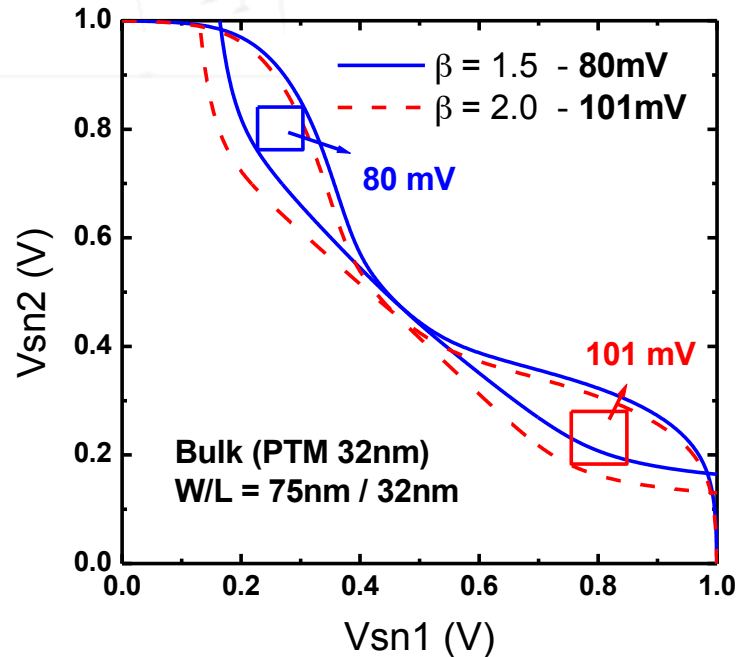
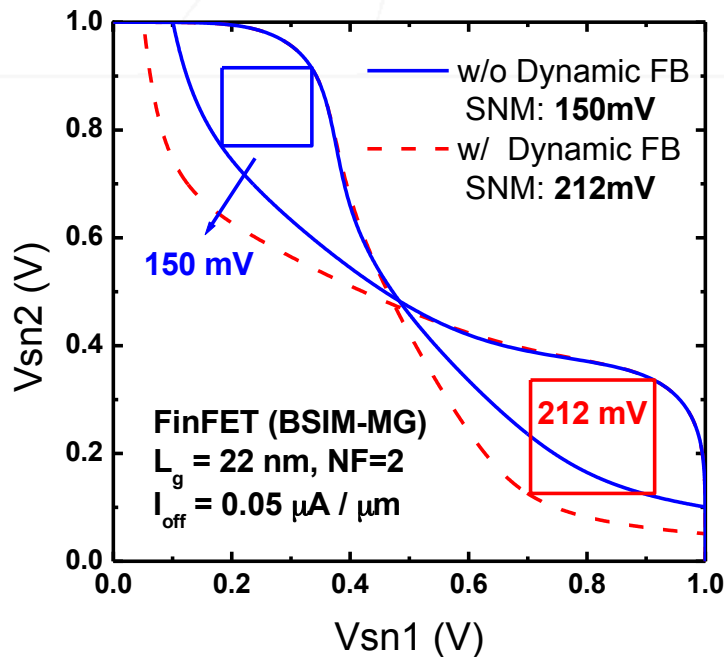
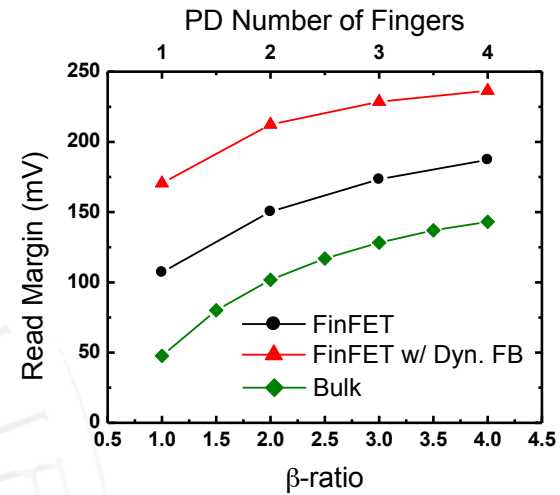
SNM improvement reported based on TCAD mixed-mode simulation.

Z. Guo, S. Balasubramanian, R. Zlatanovici, T. King, B. Nikolic,
"FinFET-Based SRAM Design," Proceedings of ISLPEP, August,
2005.



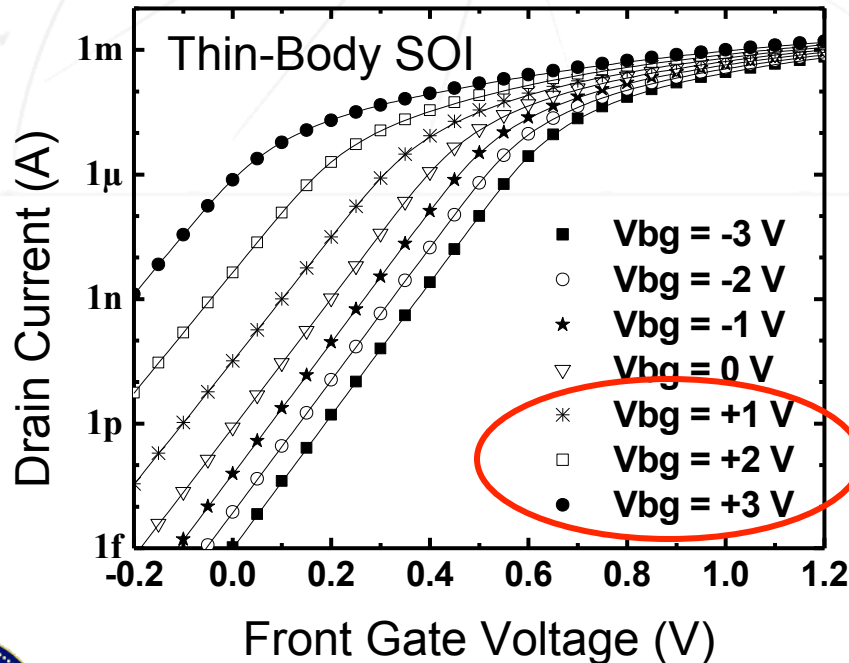
BSIM-IMG Simulation of FinFET SRAM

- FinFET-based SRAM cells are simulated using BSIM-CMG and BSIM-IMG.
- Back-gate dynamic feedback enhances the read margin from 150mV to 212mV.
- Back-channel inversion required to simulate write margin.



On-going research

- With a high back-gate bias, the double-gate SOI can enter depletion mode
 - Much higher leakage
 - But higher speed !



Symbols: TCAD

Lines: **New BSIM-IMG** with a novel iterative technique to compute the surface potential

$L_g = 10 \mu\text{m}$

$T_{ox} = 1 \text{nm}$, $T_{si} = 8 \text{nm}$, $T_{box} = 20 \text{nm}$

FG: midgap WF; BG: P+ WF



Where Are We!

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Technology Transfer

- **Release of BSIM-IMG 101 (April 2011)**
 - **Available in EDA tools:** SimuCAD, ProPlus, Accelicon
 - **Implementation In Progress @ Cadence, Synopsys**
 - **Package Ready for Technology Evaluation and Design under NDA**
 - **Verilog-A code and Well-documented Technical Manual**
 - **Provide some support and Commitment to improve the model**



Summary

- **BSIM-IMG** is a **Turnkey , Production Ready** model
 - Is submitted to the CMC for standardization
- **Physical, Scalable Core Model for FDSOI devices**
- **Plethora of Real Device Effects modeled**
- **Advanced Device Effects – Quantum, Back-gate bias**
- **Validated** on Hardware Data from two FDSOI/UTBSOI technologies
- Available **in major EDA tools**



Publications & Useful References

- **2005** *M. V. Dunga, C.-H. Lin, A. M. Niknejad and C. Hu, "BSIM-MG: A Compact Model for Multi-Gate Transistors," a chapter in FinFET and Other Multi-Gate Transistors edited by J. P. Colinge.*
- **2007** *D. D. Lu, M. V. Dunga, C-H. Lin, A. M. Niknejad and C. Hu, "A Multi-Gate MOSFET Compact Model Featuring Independent-Gate Operation", **IEDM**, December 2007*
- **2010** *D. D. Lu, C-H. Lin, A. M. Niknejad and C. Hu, " Multi-Gate MOSFET Compact Model BSIM-MG", a chapter in Compact Modeling Principles, Techniques and Applications, Springer 2010*
- **2011** *D. D. Lu, M. V. Dunga, C-H. Lin, A. M. Niknejad and C. Hu, " A Computationally Efficient Compact Model for fully-depleted SOI MOSFETs with independently-controlled front- and back-gates", Solid.State Electronics, vol. 62, no. 1, pp. 31--39, Aug 2011*



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